

Finland-Espoo: Miscellaneous general and special-purpose machinery

OJ S 96/2023 19/05/2023

Contract notice

Supplies

Legal Basis:

Directive 2014/24/EU

Section I: Contracting authority

I.1. Name and addresses

Official name: VTT Technical Research Centre of Finland Ltd

National registration number: 2647375-4

Postal address: P.O. Box 1000, VTT

Town: Espoo

NUTS code: FI1 Manner-Suomi

Postal code: 02044

Country: Finland

E-mail: kilpailutus@vtt.fi

Telephone: +358 20722111

Internet address(es):Main address: <https://www.vttresearch.com/en>**I.3. Communication**

The procurement documents are available for unrestricted and full direct access, free of charge, at: <https://tarjouspalvelu.fi/vtt?id=458678&tpk=d983cc71-c1a2-4360-aa2c-cc0d91814ddd>

Additional information can be obtained from the abovementioned address

Tenders or requests to participate must be submitted electronically via: <https://tarjouspalvelu.fi/vtt?id=458678&tpk=d983cc71-c1a2-4360-aa2c-cc0d91814ddd>**I.4. Type of the contracting authority**

Body governed by public law

I.5. Main activity

Other activity: Research and development

Section II: Object

II.1. Scope of the procurement**II.1.1. Title**

Plasma ALD

Reference number: Reg. no 33/206/2023

II.1.2. Main CPV code

42900000 Miscellaneous general and special-purpose machinery

II.1.3. Type of contract

Supplies

II.1.4. Short description

The object of the tender is a 2-chamber Plasma Enhanced Atomic Layer Deposition Cluster with Automatic Wafer Handling (later also "Equipment" and/or "Tool") for coating of 200mm wafer substrates, or substrates that can be placed on such carrier wafers, with different metals, nitrides and oxides with process separation between metals/nitrides and oxides, and wafer handling from chamber-to-chamber and chamber-to-cassette without vacuum breaking. The object of the tender process is described in more detail in the invitation to tender documents.

II.1.5. Estimated total value

Value excluding VAT: 1 600 000,00 EUR

II.1.6. Information about lots

This contract is divided into lots: no

II.2. Description

II.2.3. Place of performance

NUTS code: FI1B Helsinki-Uusimaa

Main site or place of performance: Espoo

II.2.4. Description of the procurement

The object of the tender is a 2-chamber Plasma Enhanced Atomic Layer Deposition Cluster with Automatic Wafer Handling (later also "Equipment" and/or "Tool") for coating of 200mm wafer substrates, or substrates that can be placed on such carrier wafers, with different metals, nitrides and oxides with process separation between metals/nitrides and oxides, and wafer handling from chamber-to-chamber and chamber-to-cassette without vacuum breaking. The tool must comply with technical properties and functionality, performance specifications and acceptance criteria set out in this Annex 1. The tool must also comply with the Cleanroom equipment standard safety and contamination requirements set out in Annex 2. A tender which does not meet one or more of the requirements specified in the annexes 1 and / or 2, may be rejected for failing to comply with the call for tenders.

The tool specifications are based on the following parameters or targets:

- Deposition uniformity
- Deposited film performance characteristics
- Substrate handling without errors and wafer loss
- Recipe library

The pricing of the equipment will consist of the main price for the minimum tool requirements ("total price of the equipment") and a separate price for the optional parts, features and efforts. The optional parts, features and efforts are not included in the total price of the equipment. The object of the tender process is described in more detail in the invitation to tender documents.

II.2.5. Award criteria

Criteria below

Quality criterion - Name: Price / Weighting: 100

Price - Weighting: 100

II.2.6. Estimated value

II.2.7. Duration of the contract, framework agreement or dynamic purchasing system

Duration in months: 12

This contract is subject to renewal: no

II.2.10. Information about variants

Variants will be accepted: no

II.2.11. Information about options

Options: yes

Description of options:

The contracting entity may procure the following or some of the following optional features from the contract supplier (see Annex 1):

- Optional feature 1: gas line and in-situ production of ozone (O₃) for chamber dedicated to oxides
- Optional feature 2 : integrated ellipsometry hardware for one chamber

Offering optional features is not mandatory. Optional features are not taken into account in the price comparison of tenders.

II.2.13. Information about European Union funds

The procurement is related to a project and/or programme financed by European Union funds: yes

Identification of the project: The procurement is related to EU_PREVAIL-project (Partnership for Realization and Validation of AI hardware Leadership) financed by EU funds.

II.2.14. Additional information

Additional information regarding the section II.2.7) above: Agreement shall enter into force on the latest date of signature by the Parties and shall be in force until the Equipment has been delivered and accepted, the user training has been held and agreed payment paid, excluding clauses which legal effects are meant to survive the termination or expiration of the Agreement.

Section III: Legal, economic, financial and technical information

III.1. Conditions for participation

III.1.1. Suitability to pursue the professional activity, including requirements relating to enrolment on professional or trade registers

List and brief description of conditions:

As stated in the invitation to tender documents.

III.1.2. Economic and financial standing

List and brief description of selection criteria:

Selection criteria as stated in the invitation to tender documents

III.1.3. Technical and professional ability

List and brief description of selection criteria:

Selection criteria as stated in the invitation to tender documents

III.2. Conditions related to the contract

III.2.2. Contract performance conditions

As stated in the invitation to tender documents.

Section IV: Procedure

IV.1. Description

IV.1.1.

Type of procedure

Open procedure

IV.1.3. Information about a framework agreement or a dynamic purchasing system

IV.1.8. Information about the Government Procurement Agreement (GPA)

The procurement is covered by the Government Procurement Agreement: yes

IV.2. Administrative information

IV.2.2. Time limit for receipt of tenders or requests to participate

Date: 19/06/2023 Local time: 12:00

IV.2.3. Estimated date of dispatch of invitations to tender or to participate to selected candidates

IV.2.4. Languages in which tenders or requests to participate may be submitted

English

IV.2.6. Minimum time frame during which the tenderer must maintain the tender

Duration in months: 6 (from the date stated for receipt of tender)

IV.2.7. Conditions for opening of tenders

Date: 19/06/2023 Local time: 12:05

Information about authorised persons and opening procedure: The given date is preliminary.

VTT reserves the right to change the scheduled date and time. The opening of tenders shall not be a public event.

Section VI: Complementary information

VI.1. Information about recurrence

This is a recurrent procurement: no

VI.3. Additional information

This notice has links and/or attachments listed in <https://www.hankintailmoitukset.fi/en/public/procurement/88279/notice/128779>

VI.4. Procedures for review

VI.4.1. Review body

Official name: Markkinaoikeus

Postal address: Sörnäistenkatu 1

Town: Helsinki

Postal code: 00580

Country: Finland

E-mail: markkinaoikeus@oikeus.fi

Telephone: +358 295643300

Internet address: <http://www.oikeus.fi/markkinaoikeus>

VI.5. Date of dispatch of this notice

16/05/2023